

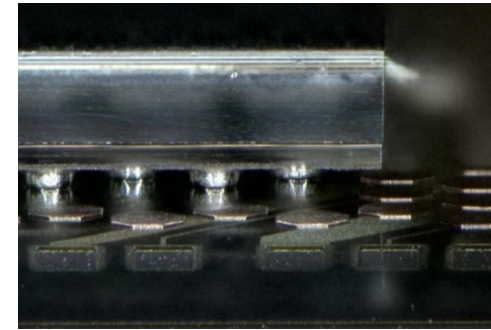




# Switcher Bumping Status

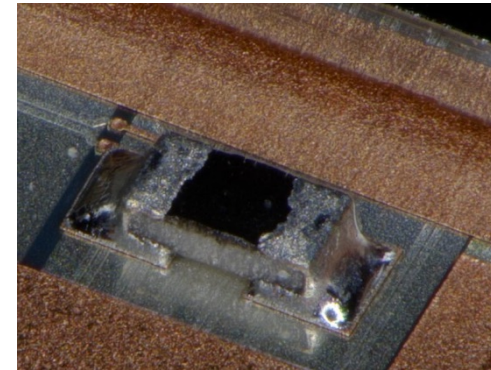
## Flip Chip of ASICs ( $\sim 240^\circ\text{C}$ ):

- ▷ Bumped ASICs have the solder balls (SAC305 and AgSn)
  - ↳ DHP bumping at TSMC, DCD bumping via Europractice
  - ↳ **SWB bumping on chip level at PacTech (????)** 
- ▷ Flip Chip of PXD modules at IZM Berlin 



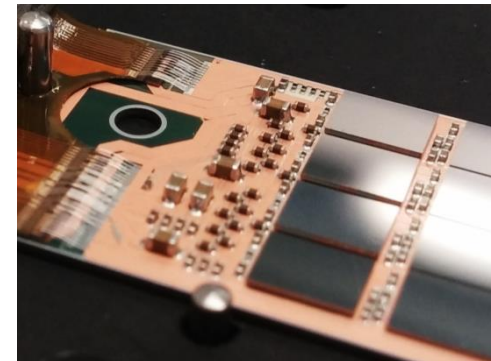
## SMD placement ( $\sim 200^\circ\text{C}$ ):

- ▷ Passive components (termination resistors, decoupling caps)
- ▷ Dispense solder paste/jetting of solder balls, pick, place and reflow
  - ↳ PbSn 37/63 solder

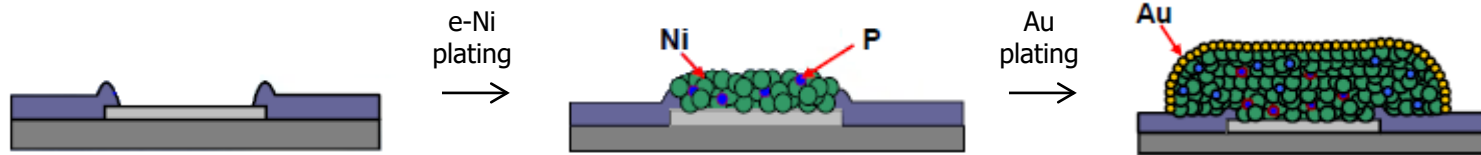


## Kapton attachment ( $\sim 170^\circ\text{C}$ ), wire bonding:

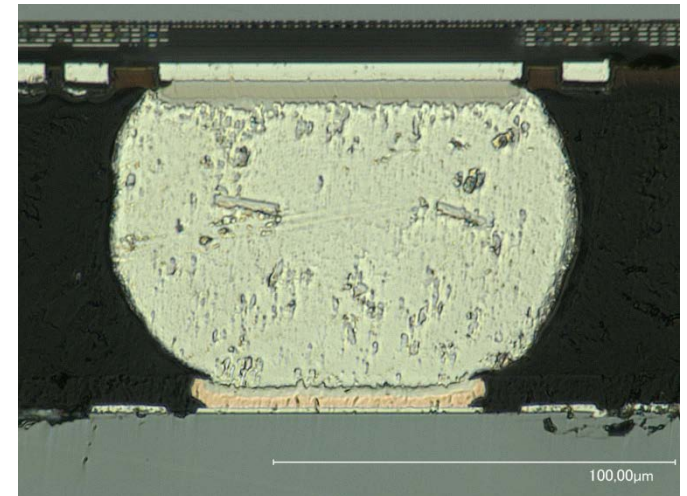
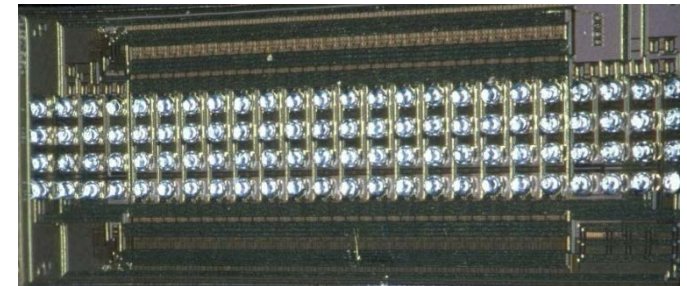
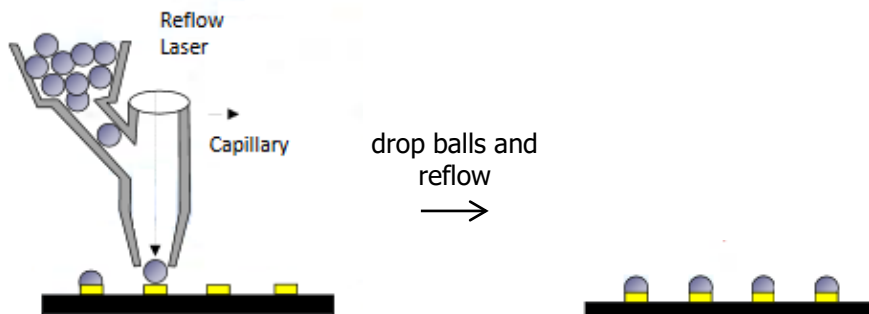
- ▷ Solder paste printing on kapton,
  - ↳ SnBi solder
- ▷ Wire-bond, wedge-wedge, 32  $\mu\text{m}$  Al bond wires



## ▷ ENIG process: Electroless Nickel Immersion Gold → UBM



## ▷ Solder ball jetting

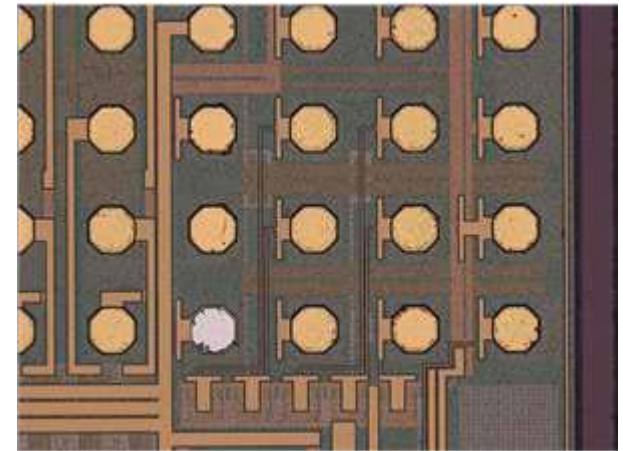


## ▷ Fully Qualified with SwitcherB18v2.0

- ↳ Test production
- ↳ X-sections, shear tests, test assemblies ... all ok!
- ↳ Assembly of EMCs, pilot modules, Desy test..

# The new SwitcherB18v2.1

- ▷ Bumping (UBM process) causes problems with the new Switcher
- ▷ On one pad – the substrate pad – and only on this pad
  - ↳ Very little or no Nickel deposition
- ▷ Main difference to old Switcher
  - ↳ Chip is wider...
  - ↳ Different passivation (1µm Nitride/Oxide <-> PI)
  - ↳ Guard ring of the chip exposed, connected to bulk

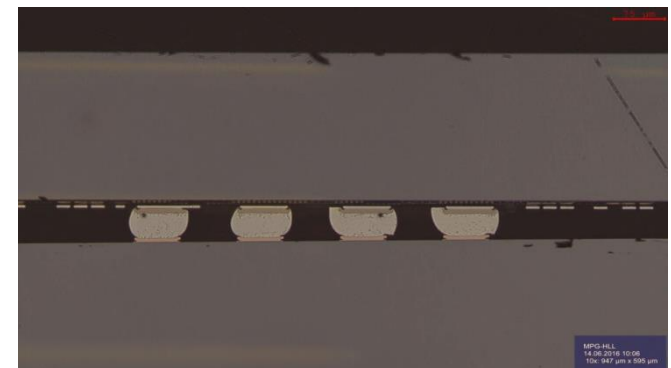
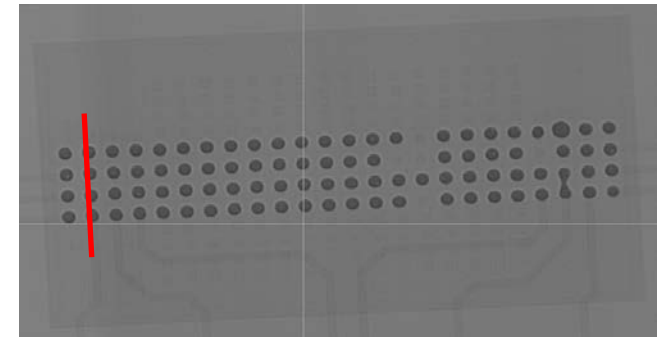
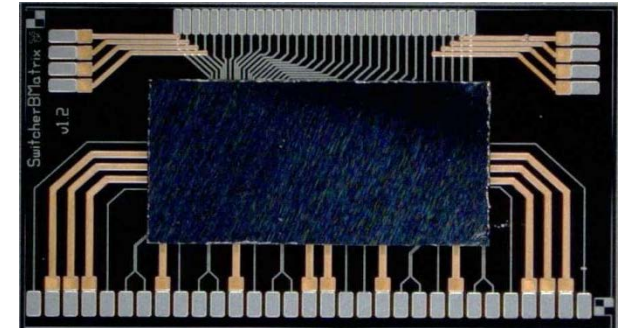


- Different electrochemical potential causes reduced Ni growth on substrate
- Solution: isolate chip edge! First trials by manual coating chip by chip ...
  - **Successful but very time consuming process with bad yield**



# Test Assembly of SWBs to bond adapter

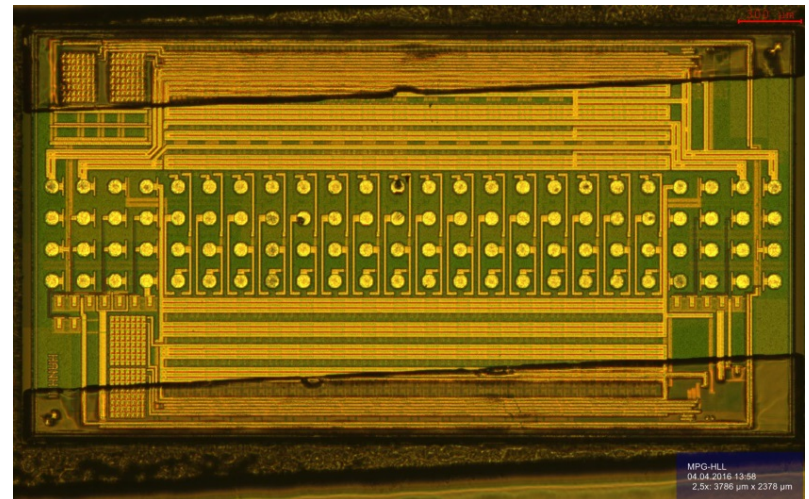
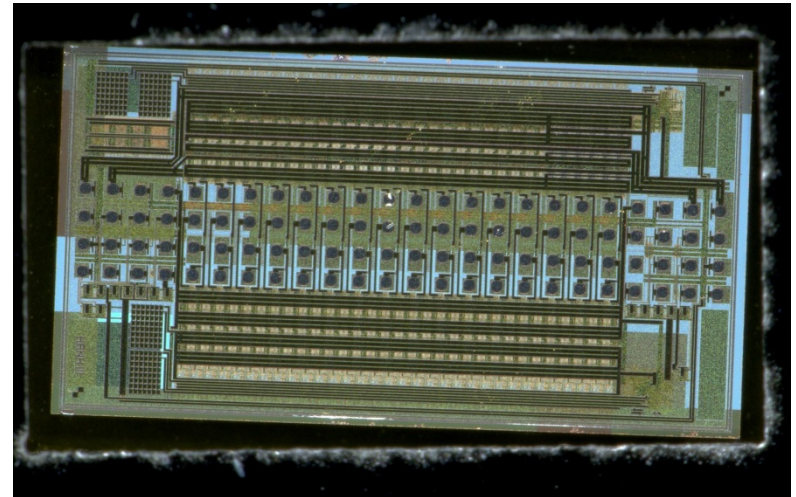
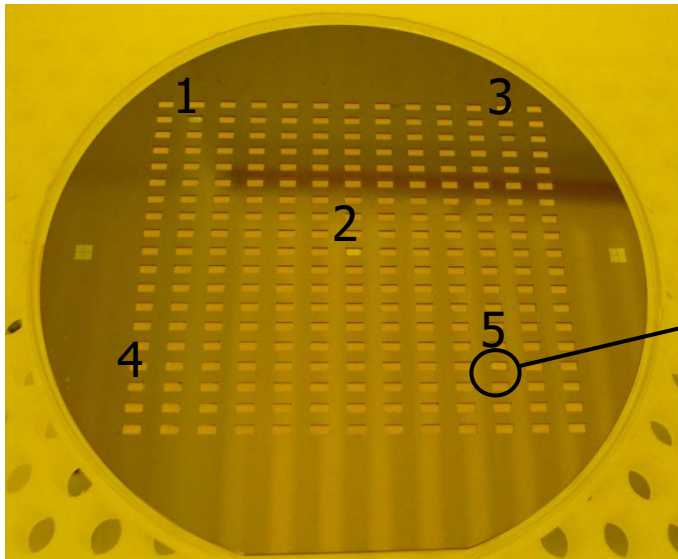
- ▷ Adapters assembled for SWB testing on hybrid level
  - ↳ Three adapters assembled
  - ↳ One assembly done with bad chip (bumping problems)
- ▷ Cross-section



- ▷ Too much solder ....

# Assembling a wafer

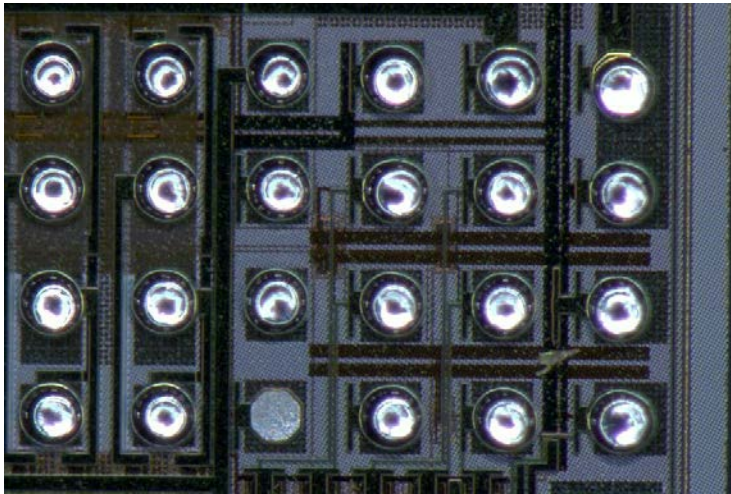
- ▷ After successful single chip coating by hand with miserable yield, trial to make it a batch process
- ▷ Re-assembly of a "wafer"



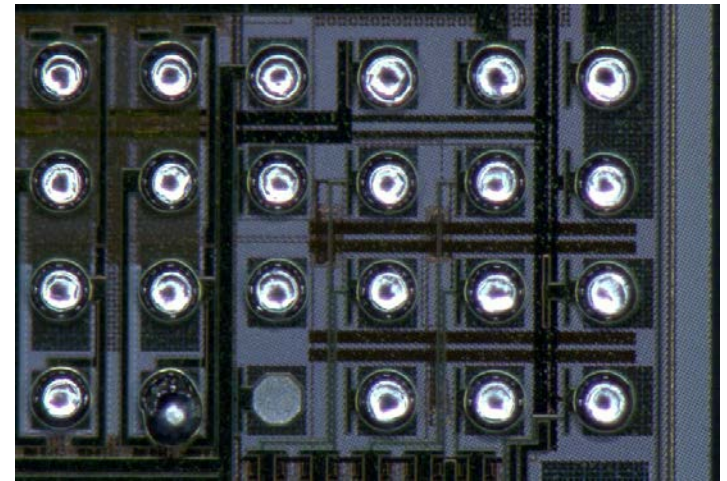
- ▷ Test successful
  - ↳ UBM successful on test wafer with five SWB
  - ↳ Balling was okay
  - ↳ Shear tests passed

## First larger batch process

- ▷ “wafer” assembled with 29/100 remaining unbumped chips
- ▷ Sent to PacTech for bumping
  - ↳ Agreed to use smaller solder balls (70  $\mu\text{m}$  and 60  $\mu\text{m}$  instead of 80  $\mu\text{m}$  now)
- ▷ **Failed!**
  - ↳ **Almost on all chips, the UBM was not deposited**



Bad UBM → no ball

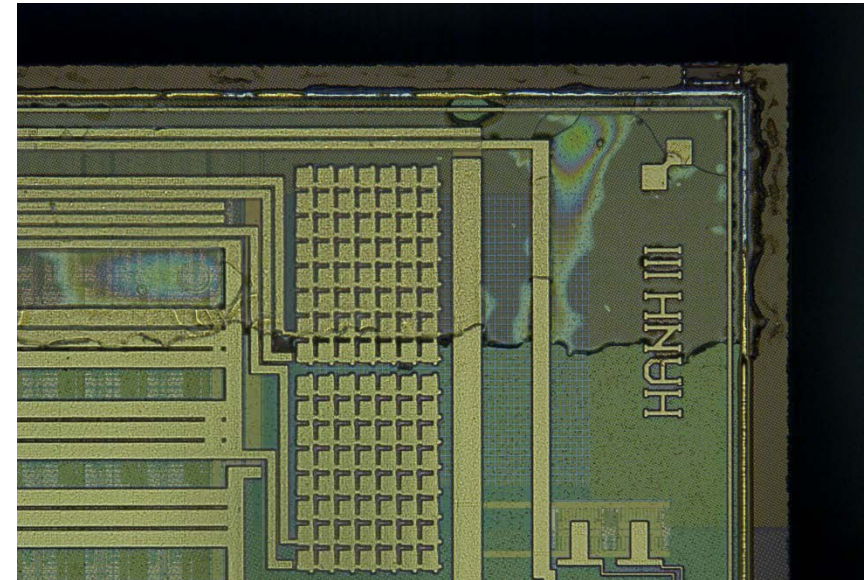
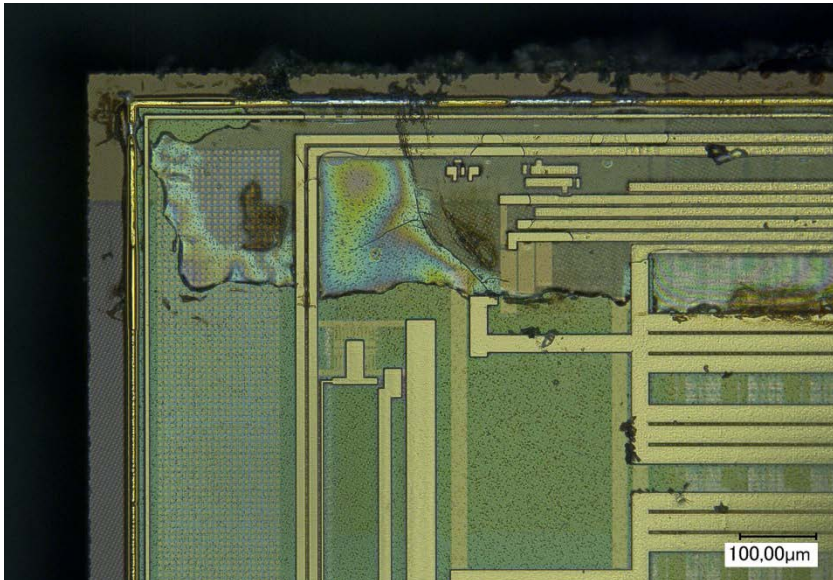


Bad UBM → no ball and double ball on neighbour



## Why did it fail?

- ▷ According to PacTech, the chemistry for the UBM is very aggressive (with little control over it) and attacks the photo resist ("occasionally")
- ▷ Isolation of the edge is compromised

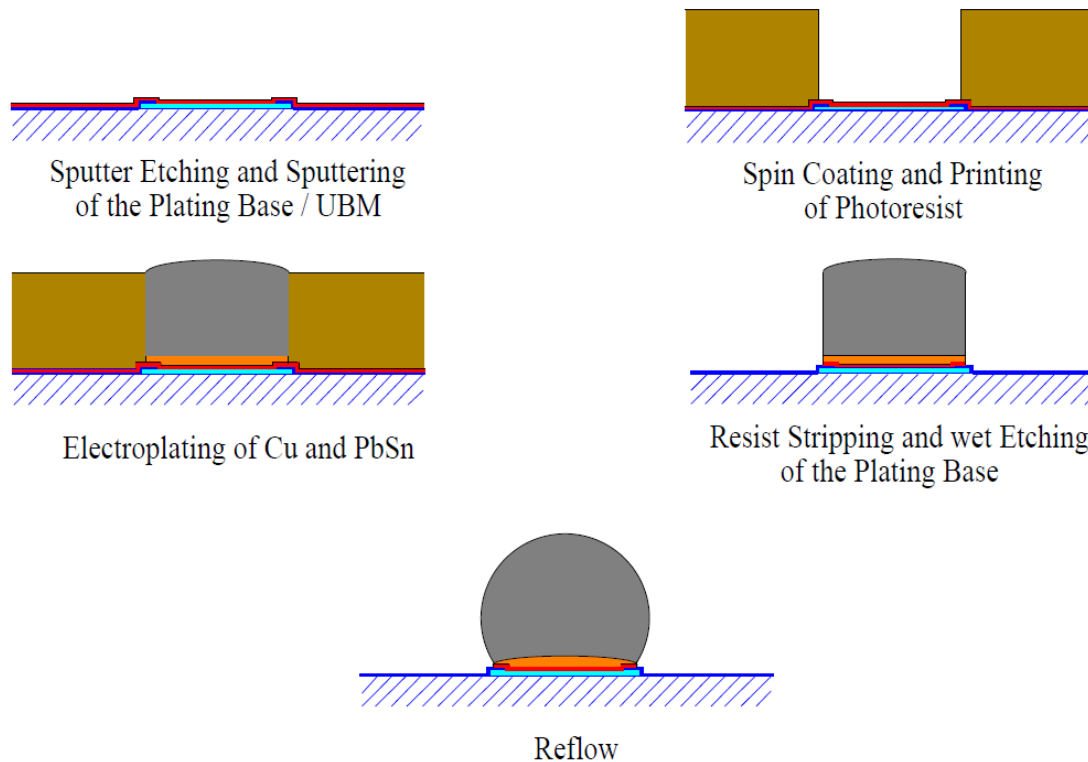


- ▷ Process is unstable, may work after some more trials (different PR ...)
- ▷ But because of manual single chip handling (wafer assembly, PR removal ..) high loss expected



# Bumping on "wafer level" at IZM

- ▷ Assemble a "wafer" by pick-and-place of Switchers to support with alignment marks
  - ↳ Accuracy ~few microns, subsequent wafer level lithography possible
  - ↳ Possibility to apply standard technology bumping by electro-plating

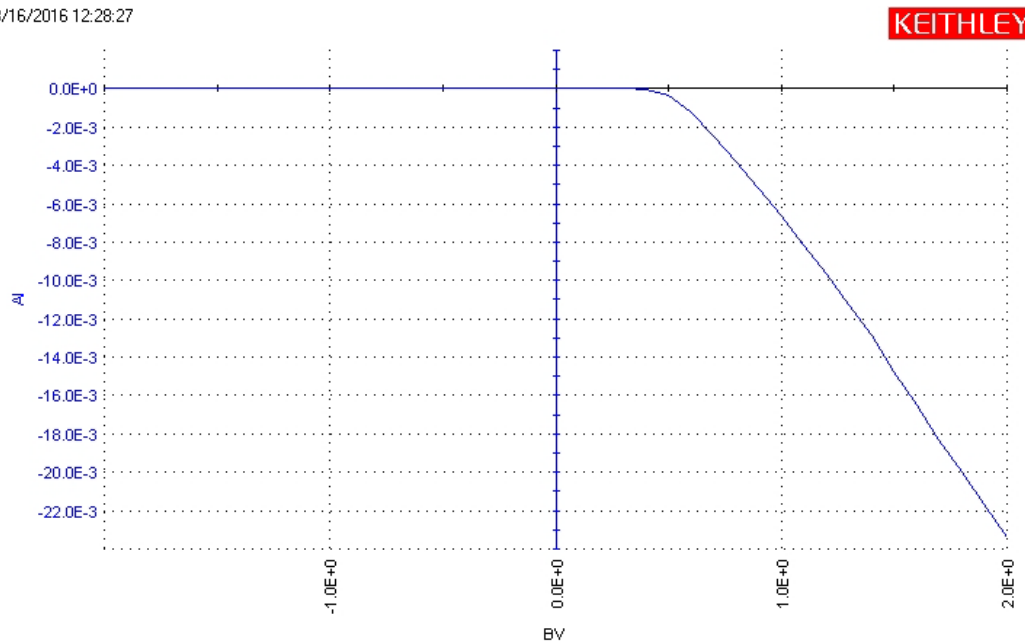


- ▷ Tests at IZM are ongoing ... litho processes to be done this week

# How to rescue the Switchers?

- ▷ Provide  $V_{\text{sub}}$  via backplane of the chip
  - ↳ Would be the most straight-forward solution
  - ↳ Unfortunately did not work (bad contact and diode structure between backplane and  $V_{\text{sub}}$ )

08/16/2016 12:28:27

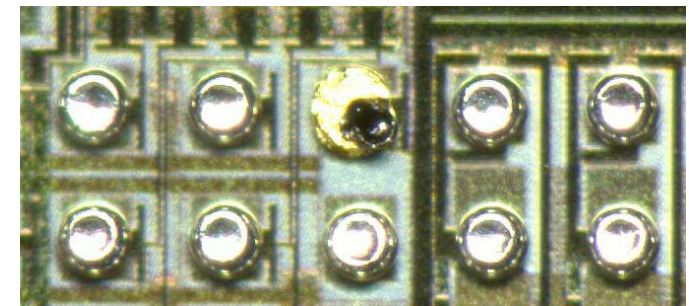
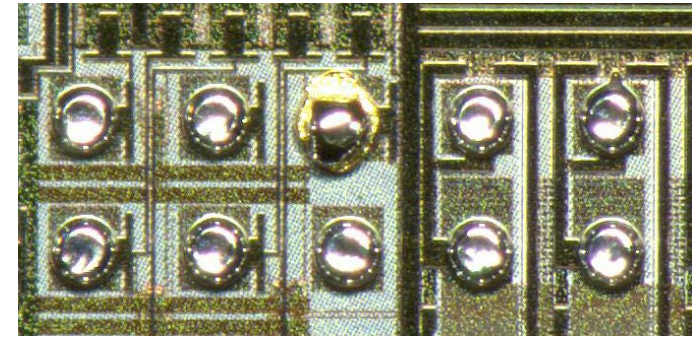
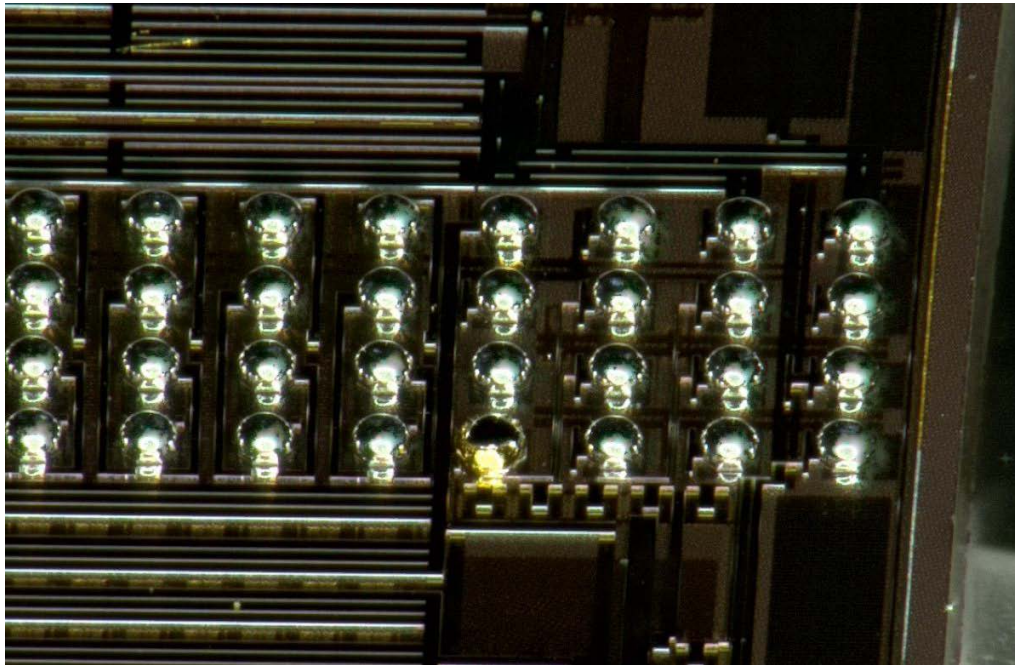


I(V) between  $V_{\text{sub}}$  and backplane,  
GND on back

- ▷ Place Au stud on missing UBM pad and deposit small solder ball on it
  - ↳ Au stud at HLL, solder ball jetting at PacTech

# Single pad balling

- ▷ Selected optically good chips
- ▷ It worked – sort of...



- ▷ Balls are all about 40-50  $\mu\text{m}$ , as the others
- ▷ Mostly central ....
- ▷ Need for testing → KIT
- ▷ Have now: 16 Au-stud chips, 12 from first batch w/ manual PR coating



- ▷ Bumping on chip level is difficult!!
- ▷ PacTech bumping worked on SWB2.0 but failed for 2.1 (passivation)
  - ↳ Work around done small number of chips
  - ↳ If tests positive, assembly of phase 2 modules can start ...
- ▷ Exploring new technique at IZM, seems feasible but remains to be shown
- ▷ To be on the safe side: order more switchers?? Engineering run??? Time scale???

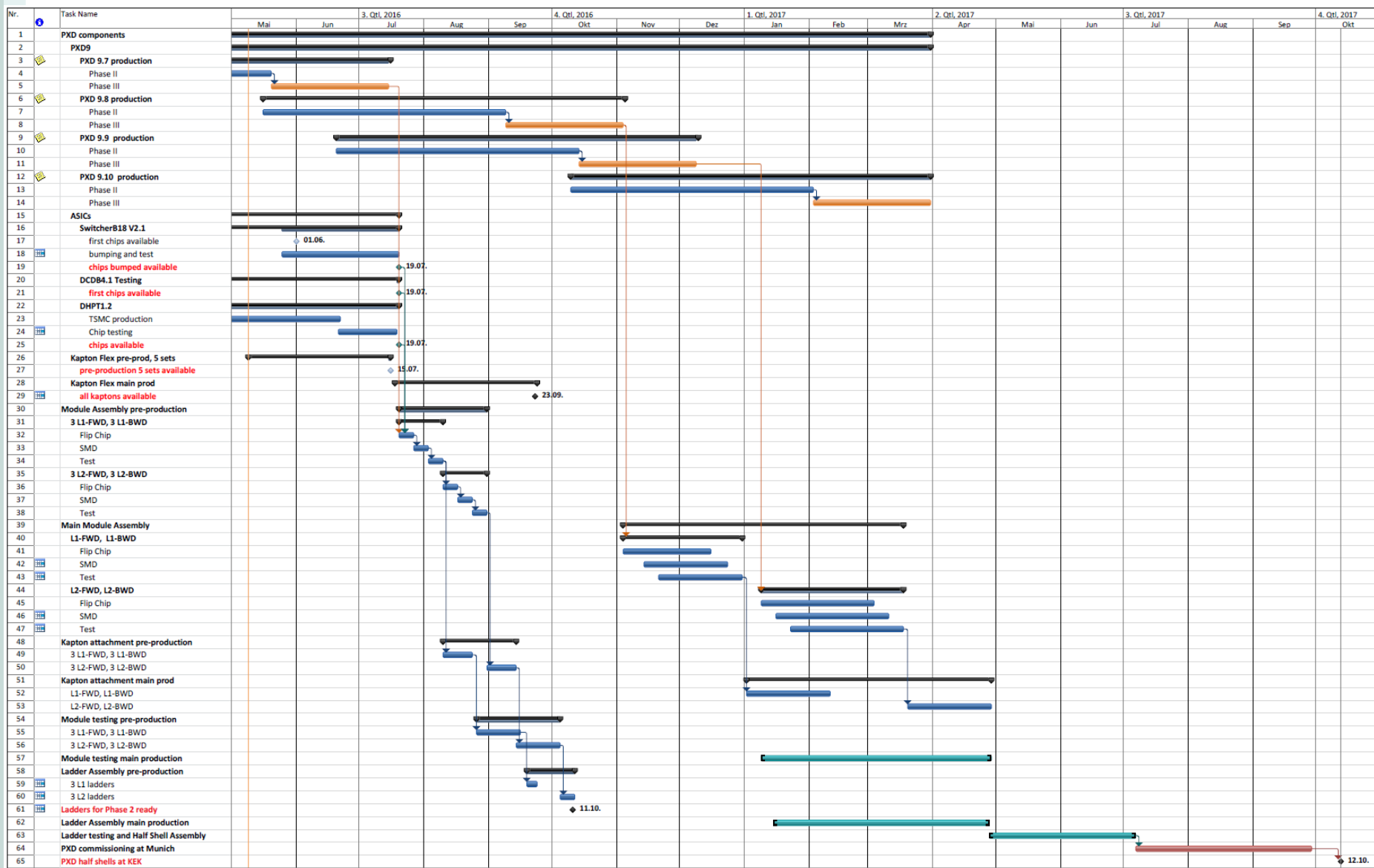


backup





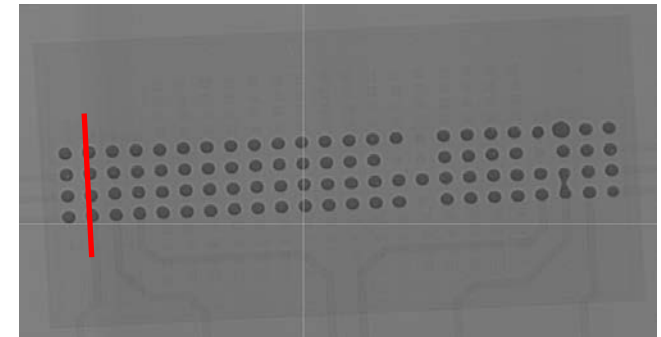
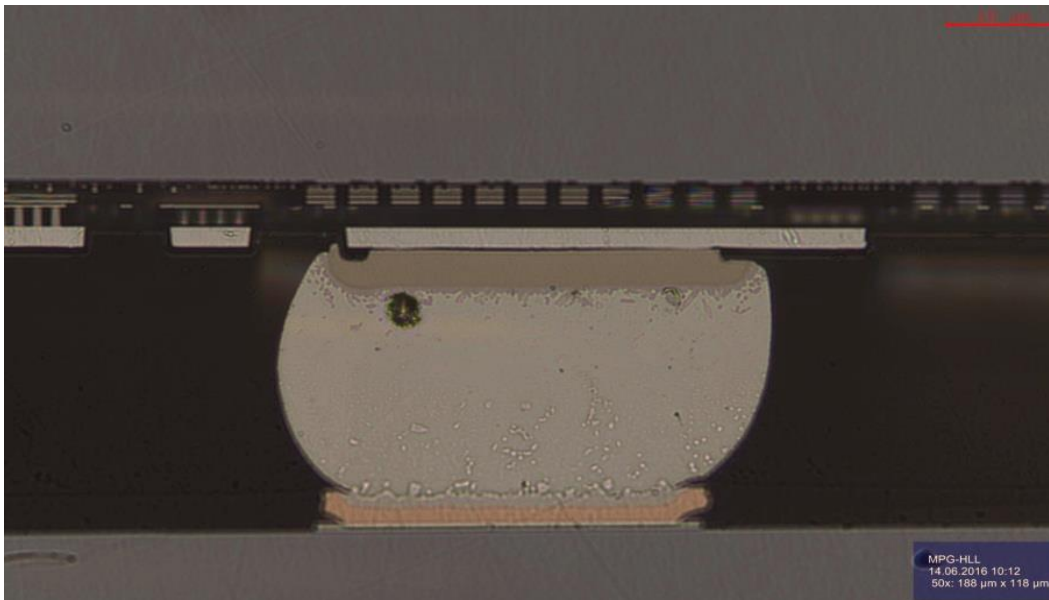
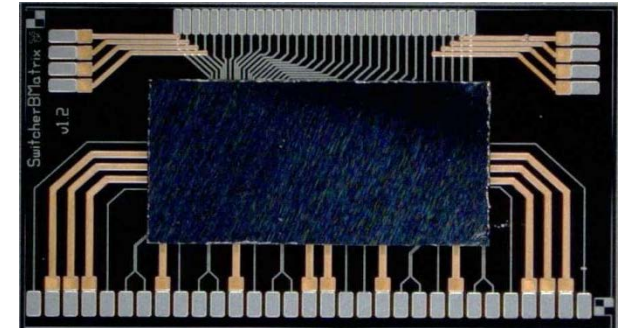
# schedule – spring 2016





# Test Assembly of SWBs to bond adapter

- ▷ Adapters assembled for SWB testing on hybrid level
  - ↳ Three adapters assembled
  - ↳ One assembly done with bad chip (bumping problems)
- ▷ Cross-section



- ▷ Delamination between SWB Alu and Ni?